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<http://link.springer.com/article/10.1007/s12541-014-0485-8>

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Development of MOEMS technology in maskless -

David Smith and Dieter Klenk "Development of MOEMS technology in maskless lithography", Proc. SPIE 7210, Emerging Digital Micromirror Device Based Systems and
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EIPBN 2012 Program . Yijian Chen, Yashesh Shroff: High Volume Nanoimprint Lithography technology and applications: Torbj rn Eriksson,
<http://eipbn.org/2012/program/>

On-Demand Data Pumping for Digital Micromirror -

The maskless lithography technology requires the management and J. Slaughter, Emerging Digital Micromirror Device (DMD) Applications Proc. SPIE
http://serisc.org/journals/IJMUE/vol9_no8_2014/14.pdf

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Patent US5870176 - Maskless lithography - Google -

The present invention provides a method for maskless lithography. Each micromirror in the two-dimensional array can be light processing technology:
<http://www.google.com/patents/US5870176>

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Programming Reversibly Self-Folding Origami with Micropatterned Photo-Crosslinkable via maskless lithography using a Science and Technology
<http://onlinelibrary.wiley.com/doi/10.1002/adma.201403510/full>

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Books: Maxwell's Reunion (Paperback) by M J Trow -

Lestrade and the Magpie (The Lestrade Mystery Series) (Hardcover) ~ M. J. Trow (Author)

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Patent US6312134 - Seamless, maskless lithography -

Seamless, maskless lithography system using spatial light modulator Deformable Micromirror Device Technology. The Deformable Micromirror Device (DMD)

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Proceedings of SPIE Volume 6151 -

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ASML, Micronic scrap standalone maskless tool -

ASML, Micronic scrap standalone maskless ASML and Micronic are still developing micromirror technology for use in maskless technology. Maskless lithography

http://www.eetimes.com/document.asp?doc_id=1194296

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<http://information5.com/m/maskless-lithography-pdf.pdf>

Patent US6965468 - Micromirror array having -

Micromirror array having reduced gap between adjacent micromirrors of maskless lithography and of the micromirror during an exemplary fabrication

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Olav Solgaard's Profile | Stanford Profiles -

Effects of through-focus symmetry in maskless lithography using micromirror MEMS Technology Solgaard, O. 2002; Micromirror Array Dynamics of pulse

<https://profiles.stanford.edu/olav-solgaard>

Optics InfoBase: Applied Spectroscopy -

Applied Spectroscopy of a high-density beam spot array in digital maskless lithography. Corrections for Digital Micromirror Device-based Maskless

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<http://www.amazon.it/Micromirror-Technology-Maskless-Lithography-Fabrication/dp/3639513657>

IEEE Xplore: Microelectromechanical Systems, -

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Deep Wet Etching in Hydrofluoric Acid, Nitric -

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Proposal of Distributed Architecture for -

Proposal of Distributed Architecture for Micromirror Image Generation in Maskless in order to utilize maskless lithography technology into large

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for the first time through Immersion lithography, polarization control will be template fabrication technology using maskless lithography

<http://dl.acm.org/citation.cfm?id=1745128>

Micro-mirror Arrays for Maskless Lithography -

Micro-mirror Arrays for Maskless Lithography B. J. Warlick and J. Garrett process technology to scale CMOS. The Fedder process leverages that scaling.

<http://diyhpl.us/~bryan/papers2/mems/Micro-mirror%20arrays%20for%20maskless%20lithography.pdf>

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We propose a programmed syringe pumps system for diffusion-based concentration control lithography techniques: Jing Chen, fabrication technology

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EUV Maskless Lithography Yijian Chen fabrication results and the dynamics study of electrically-damped double-comb micromirrors for EUV maskless lithography.

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SOI-CMOS-MEMS | Peter Gilgunn - Academia.edu -

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Micromirror Technology for Maskless Lithography Yijian Chen This book presents a complete analysis and review of dynamics, control and fabrication of

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on Information Storage and Processing nano fabrication. Recently, lithography technology is maskless lithography technology has

<http://proceedings.asmedigitalcollection.asme.org/volume.aspx?volumeid=16621>

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Advanced Patent Search. Patents

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